



Atty. Dkt. No.: AMAT/4666/ETCH/CHMBR/JBT

8 Bpm 1763
PATENT
AT/4666/ETCH/CH/MBR/JB1
2/2/23

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Mohn, et al.

Filed: July 7, 2000

For: Multi-Purpose Processing Chamber
with Removable Chamber Liner

Commissioner for Patents
Washington, D.C. 20231

§§§ Group Art Unit: 1763
§§§ Examiner: T. Dang

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CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on January 27, 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231.

1/27/03

Kent & Tuckett
Signature

Dear Sir:

RESPONSE TO OFFICE ACTION DATED OCTOBER 25, 2002

In response to the Office Action dated October 25, 2002, having a shortened statutory period for response set to expire on January 27, 2003, Applicant requests entry and consideration of the following amendments and remarks. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/4666/ETCH/CHMBR/KMT, \$138.00 for 1 additional independent claim and 3 total additional claims, and any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE CLAIMS:

02/04/2003 RMEBRAHT 00000081 200782 09611817

Please amend the claims as follows:

01 FC:1201 84.00 CH
02 FC:1202 54.00 CH

1. (Amended) An apparatus for processing a semiconductor substrate, comprising:

a chamber body having an internal volume defined by first and second substantially cylindrical regions and by side walls extending substantially tangent between the first and second substantially cylindrical regions;